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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Application of :  
Takashi KAITO et al. :  
Serial No. 10/759,354 : Group Art Unit - 1763  
Filed: January 16, 2004 : Examiner - Ram N. Kackar  
For: METHOD AND SYSTEM FOR :  
SURFACE OR CROSS- :  
SECTIONAL PROCESSING :  
AND OBSERVATION : Docket No. S005-5191

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Mail Stop AMENDMENT  
COMMISSIONER FOR PATENTS  
P.O. Box 1450  
Alexandria, VA 22313-1450

RESPONSE

S I R:

In response to the Office Action mailed December 28, 2005, applicants amend their application as follows:

ADDITIONAL FEE:

No additional fees are believed required; however, should it be determined that a fee is due, authorization is hereby given to charge any such fee to our Deposit Account No. 01-0268.

MAILING CERTIFICATE ON PAGE 4

**ELECTION OF INVENTION AND SPECIES:**

In response to the restriction and election requirements, applicants provisionally elect, with traverse, Invention I drawn to a method and list claims 1-8 as being readable on the elected invention, and Species A directed to the focused energy beam being a focused ion beam and list claims 1-8 as being readable on the elected species.